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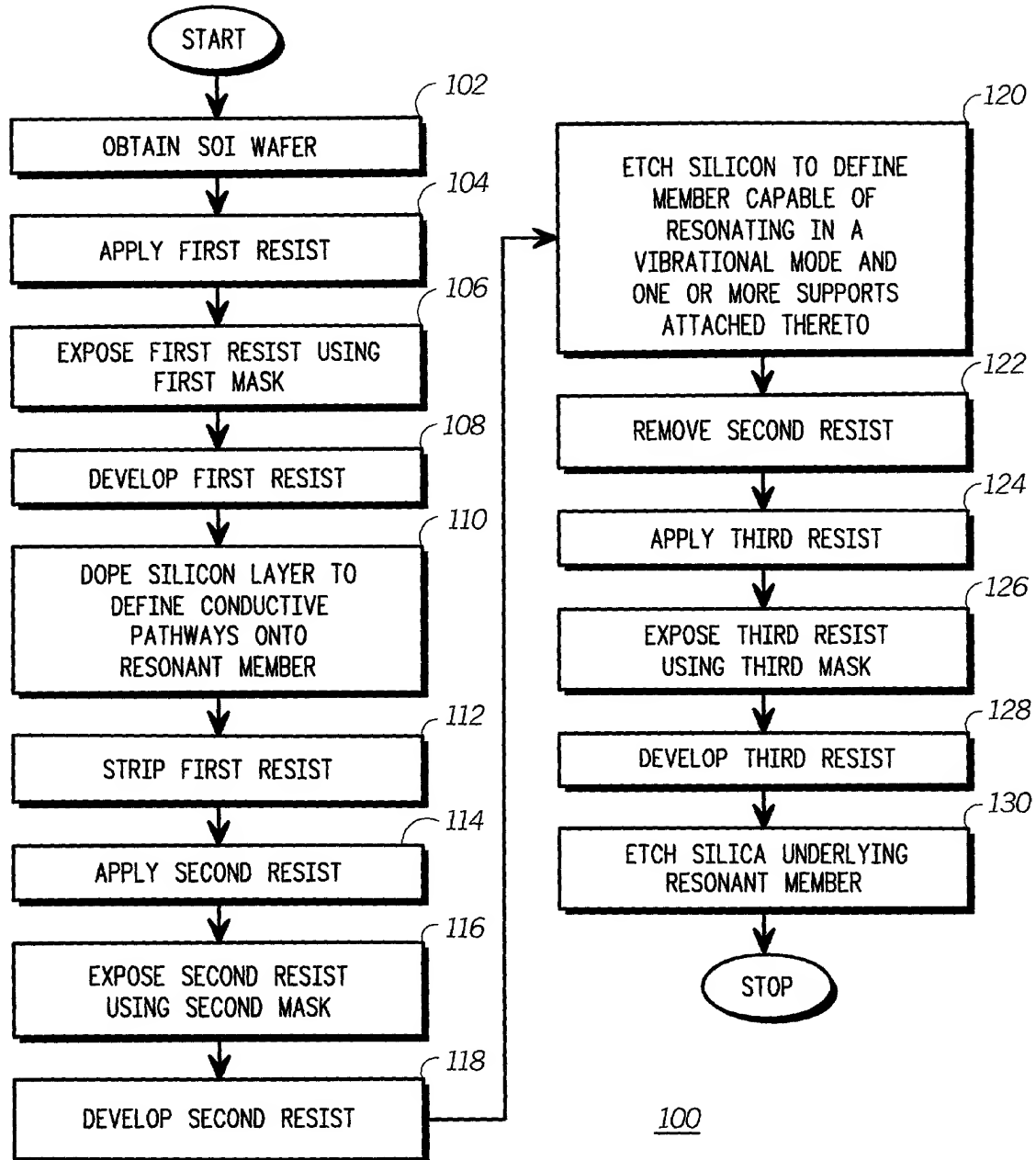


FIG. 1

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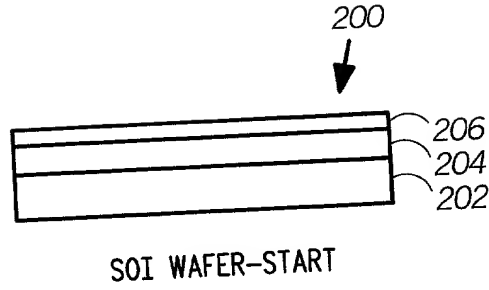


FIG. 2

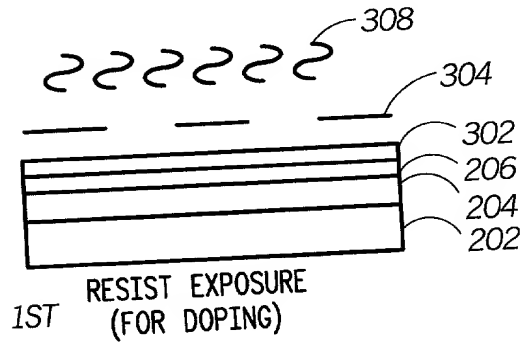


FIG. 3

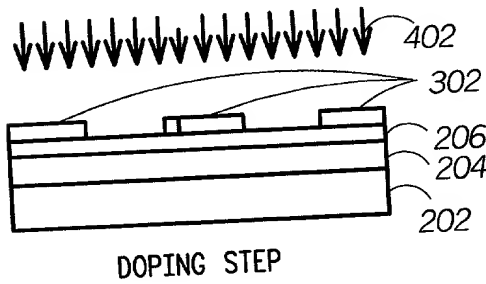


FIG. 4

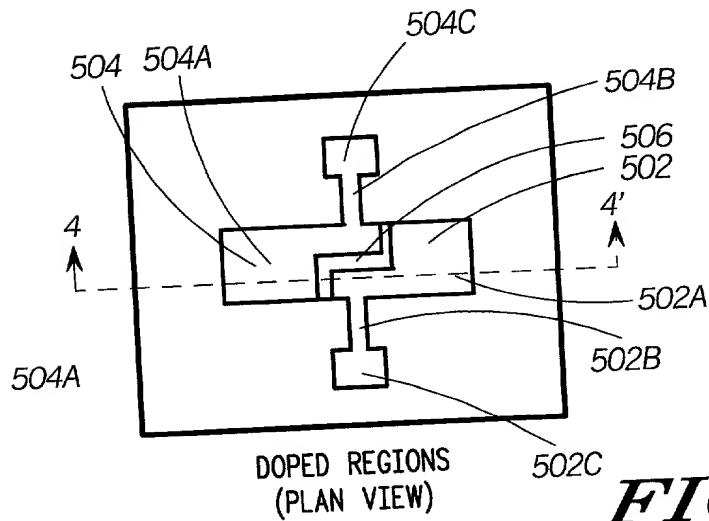


FIG. 5

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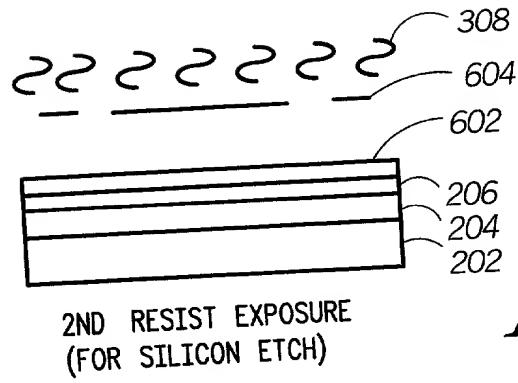


FIG. 6

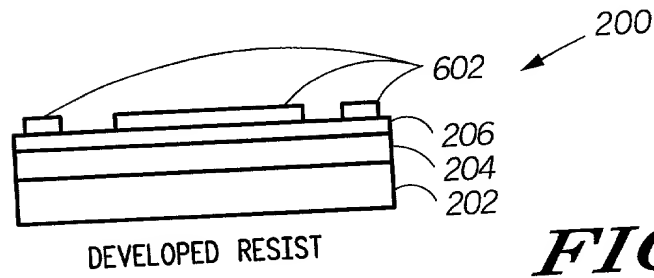


FIG. 7

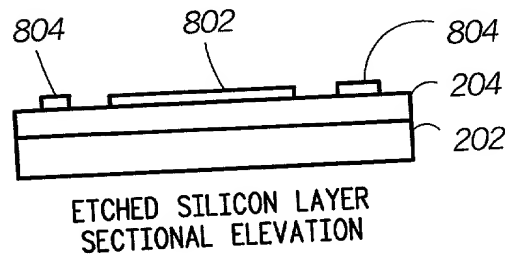


FIG. 8

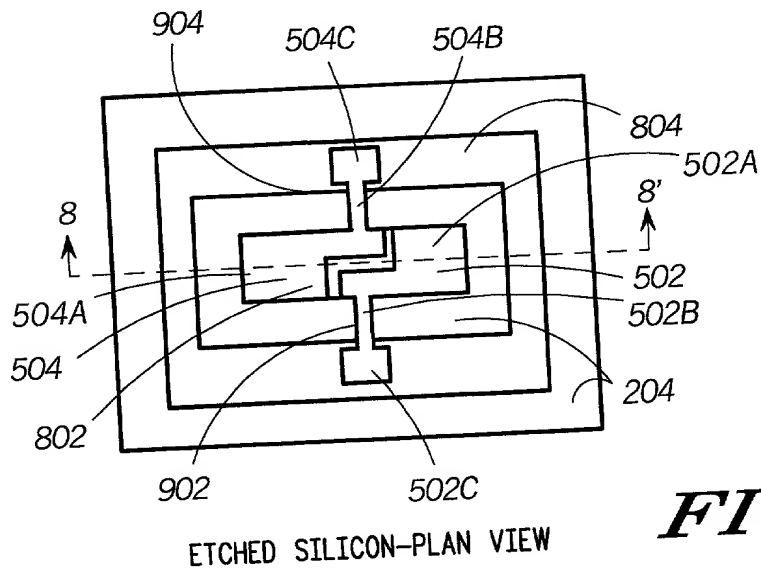
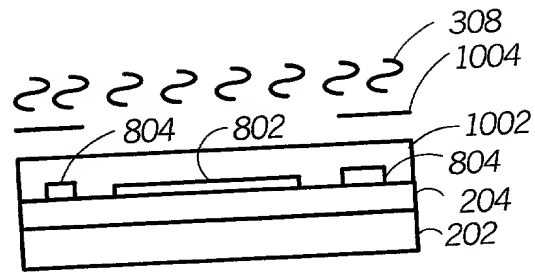


FIG. 9

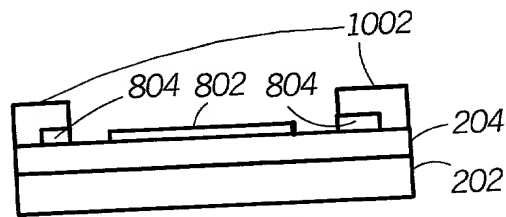
0982843.040904

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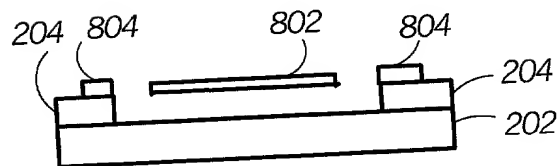
3RD RESIST EXPOSURE
(FOR SI02 ETCH)

FIG. 10



DEVELOPED RESIST

FIG. 11



AFTER SI02 ETCH

FIG. 12



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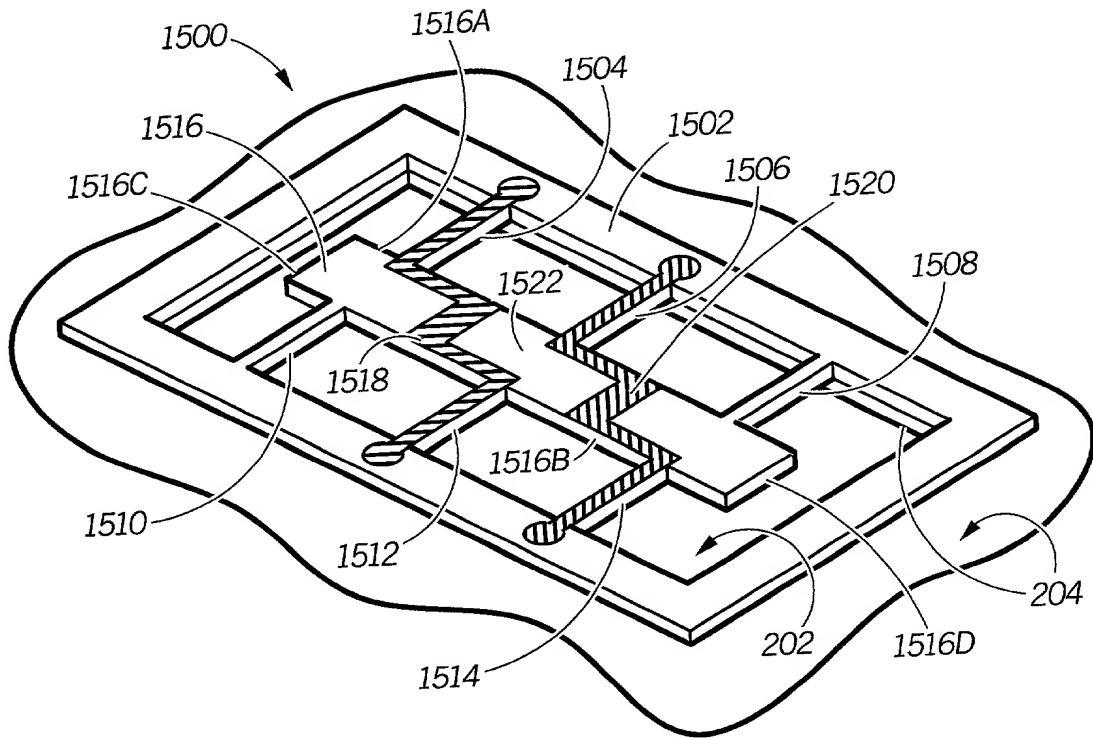


FIG. 15

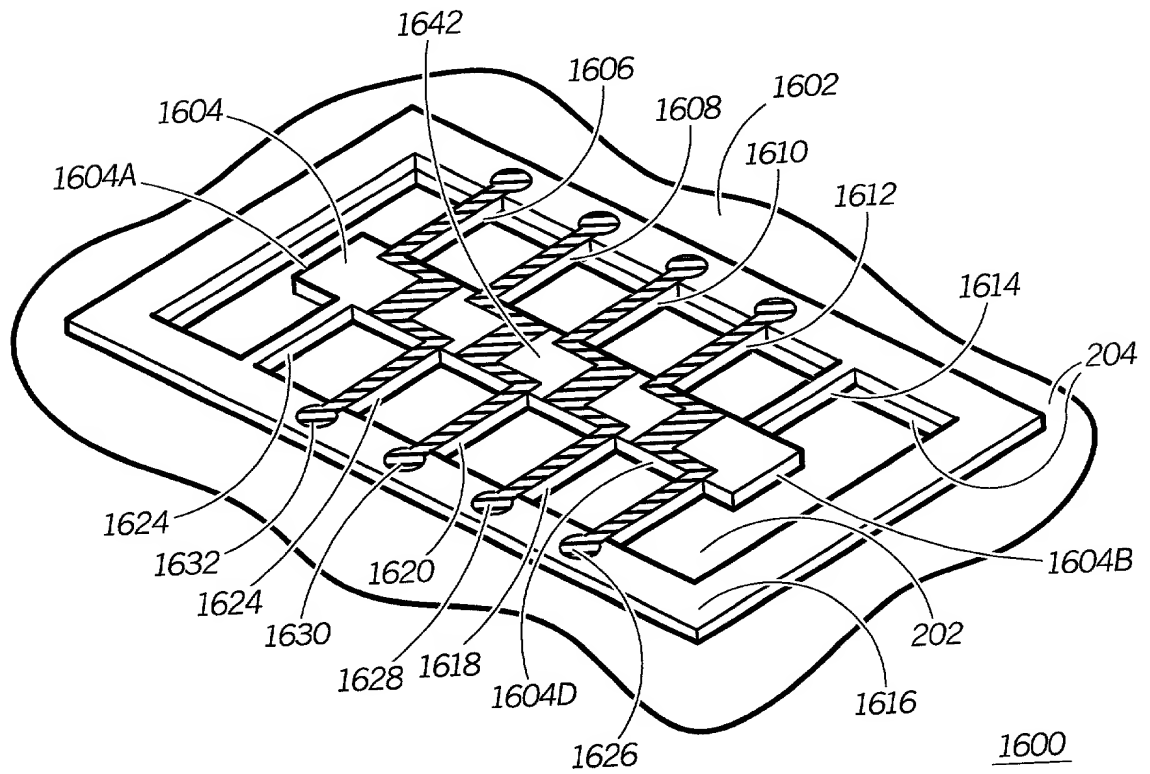


FIG. 16

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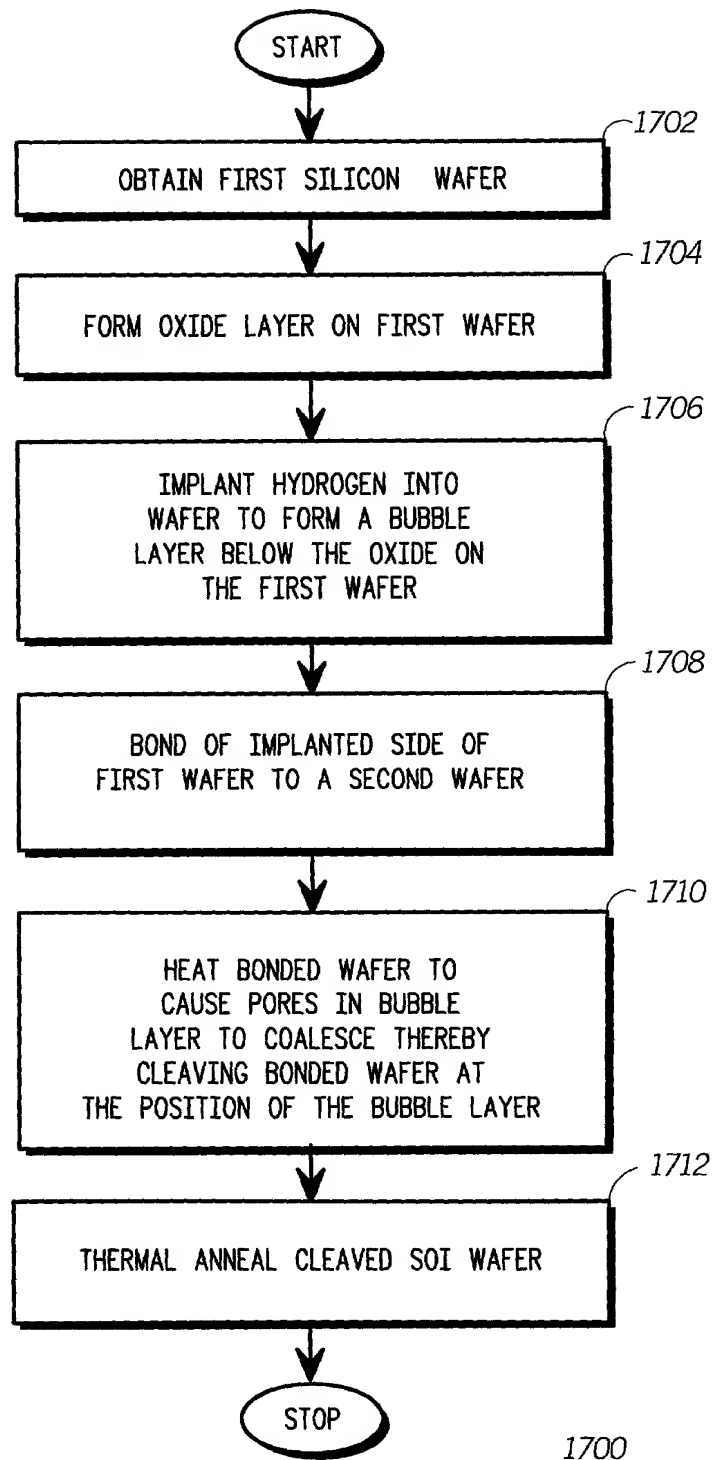


FIG. 17

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FIG. 18

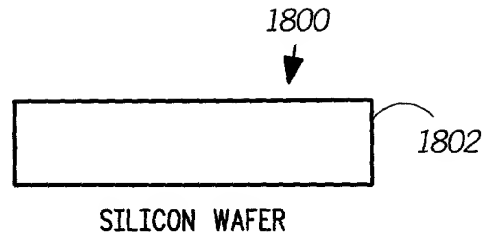


FIG. 19

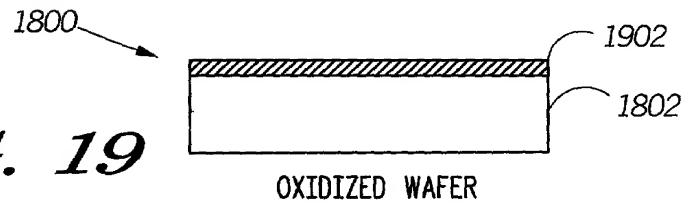


FIG. 20

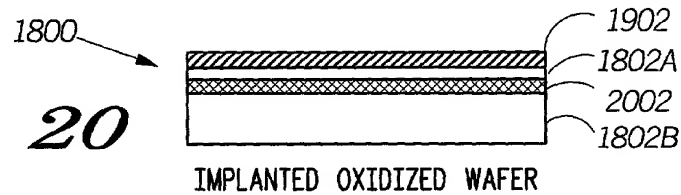


FIG. 21

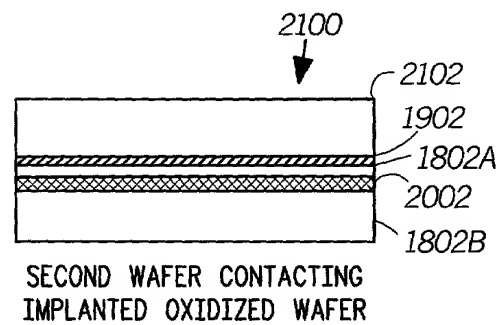
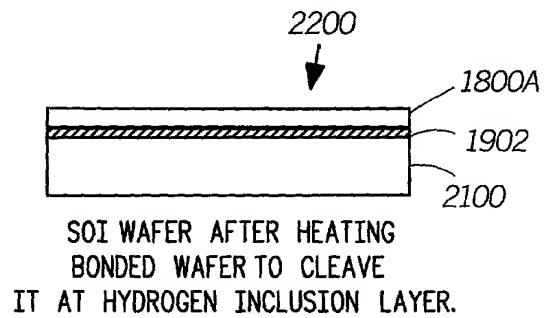


FIG. 22



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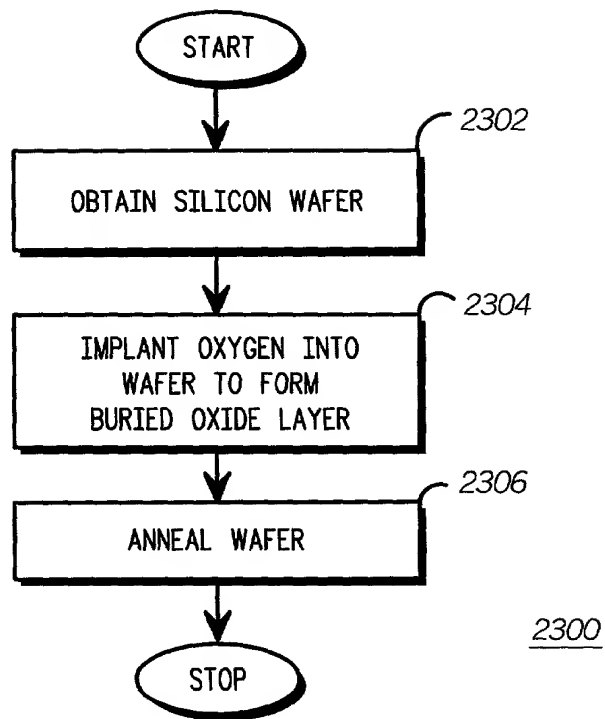


FIG. 23

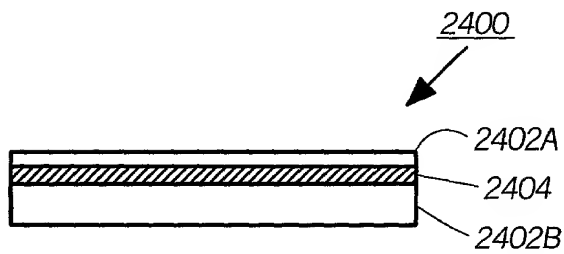
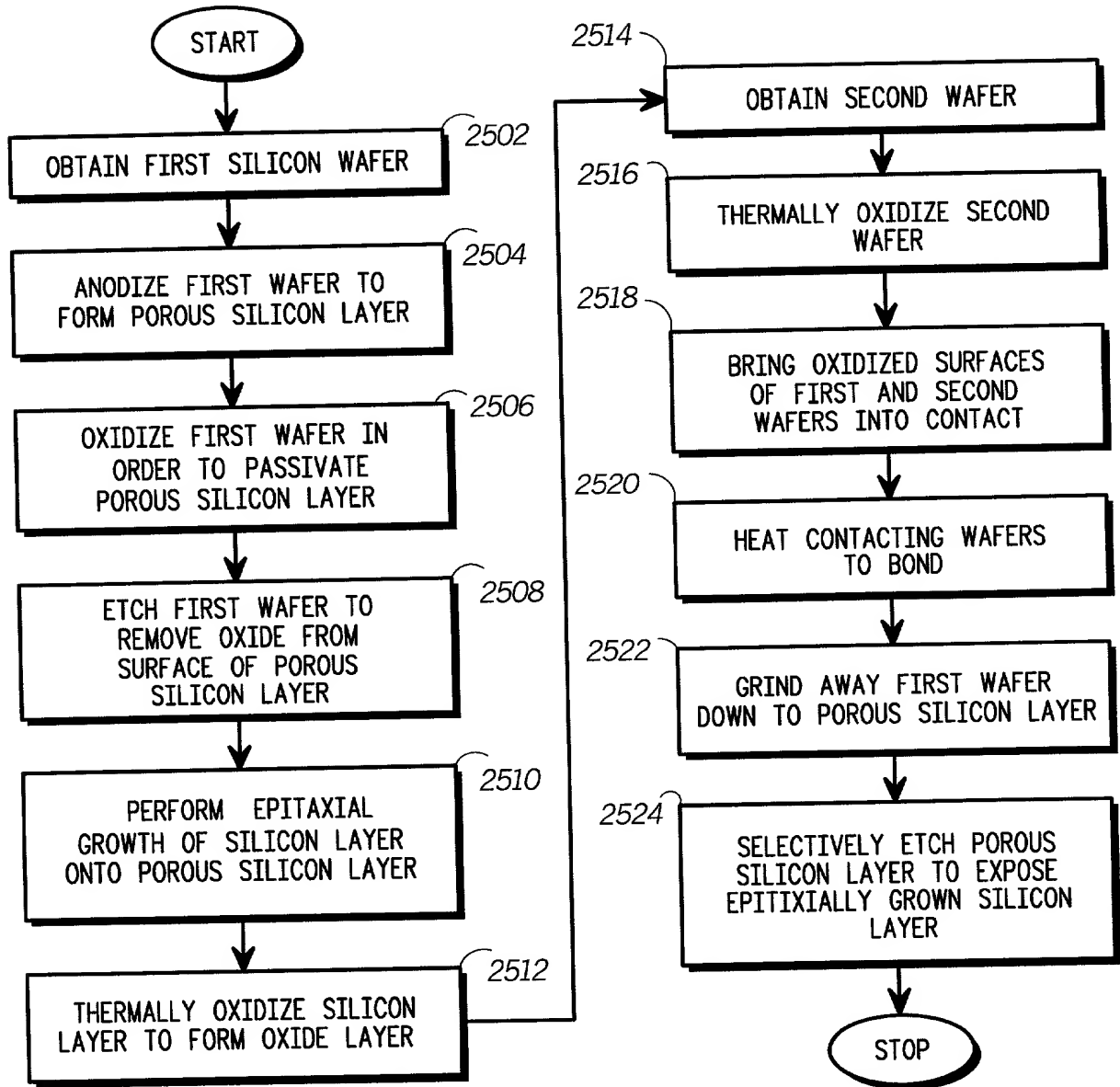


FIG. 24

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FIG. 25

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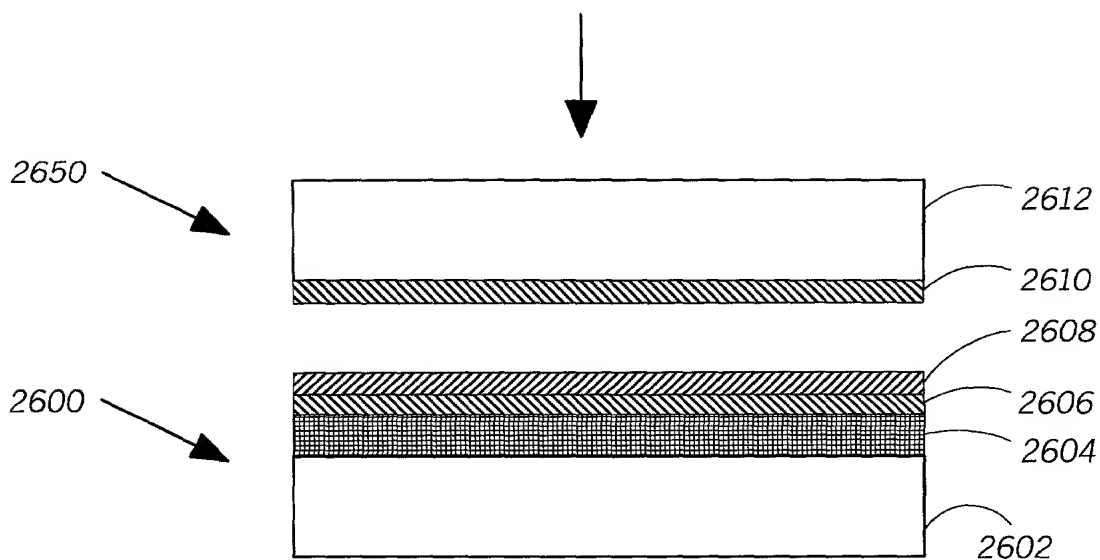


FIG. 26

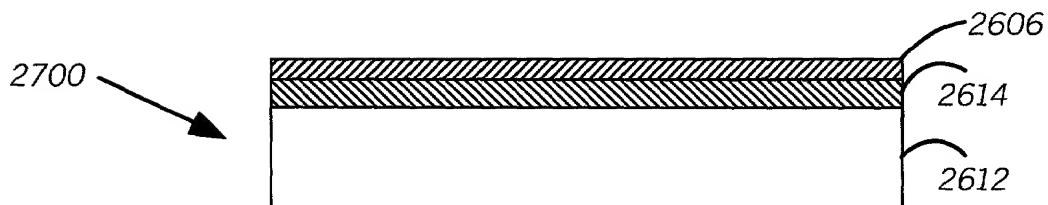


FIG. 27

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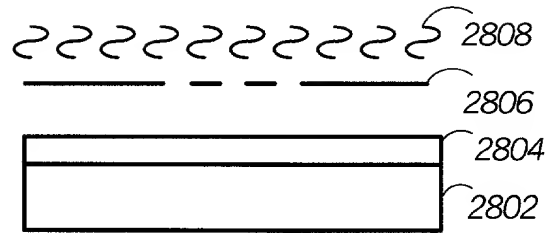


FIG. 28

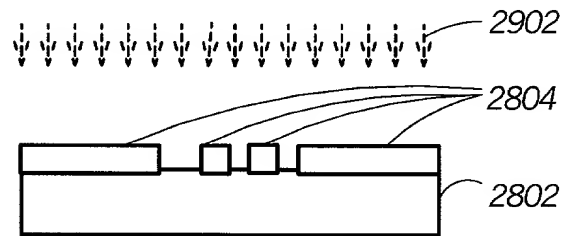


FIG. 29

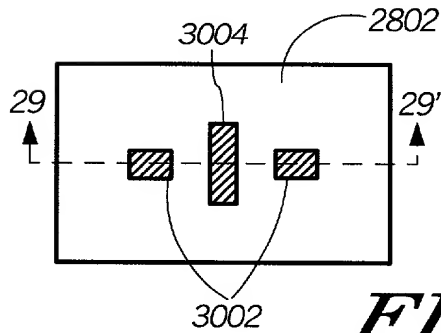


FIG. 30

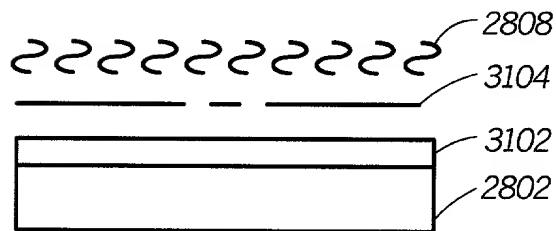


FIG. 31

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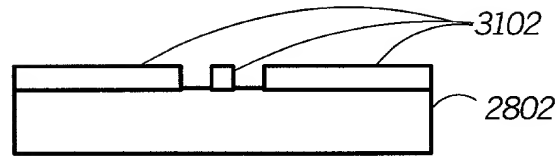


FIG. 32

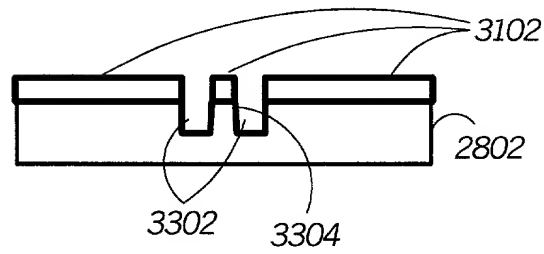


FIG. 33

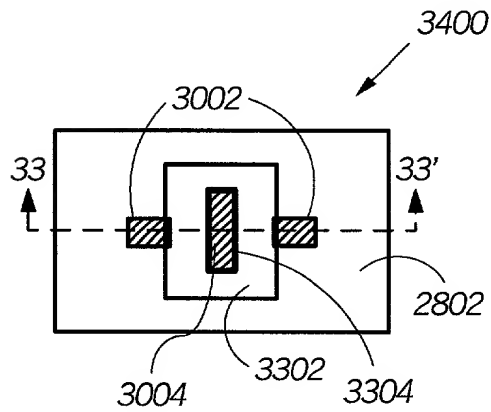


FIG. 34

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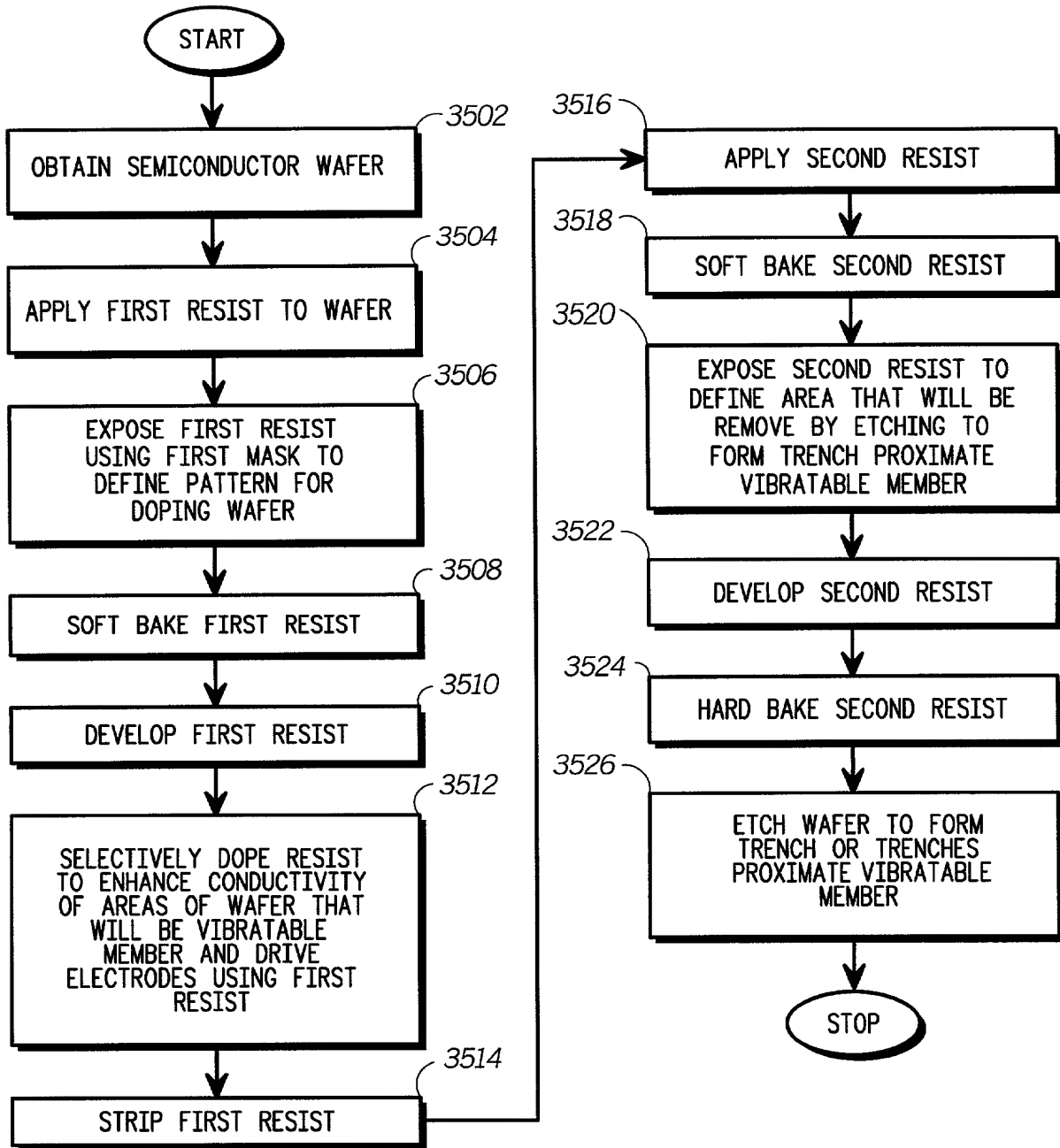


FIG. 35

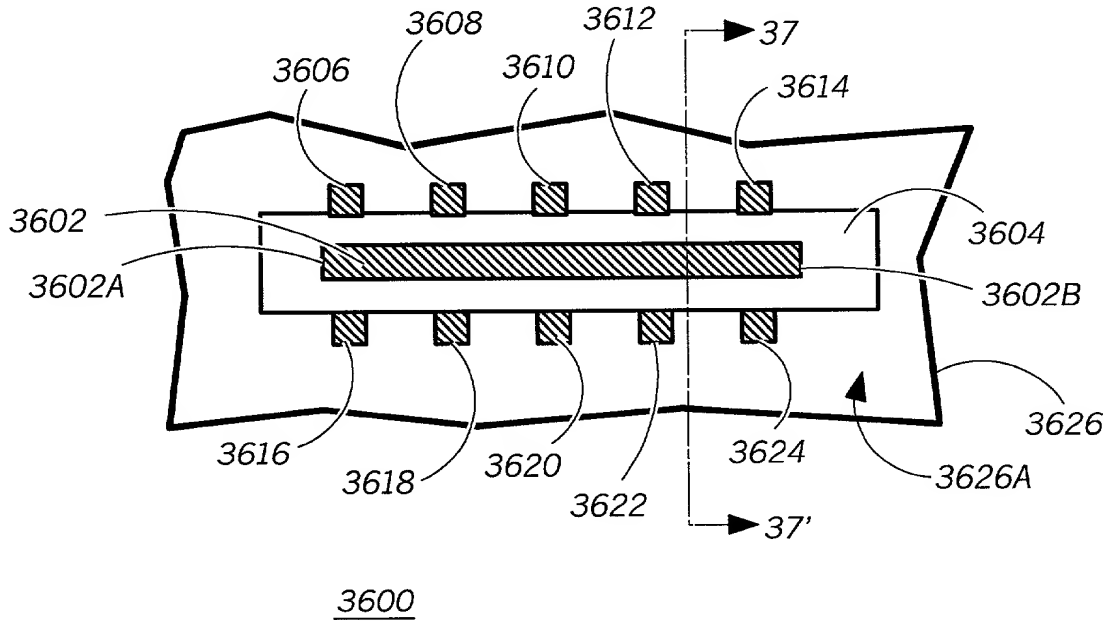


FIG. 36

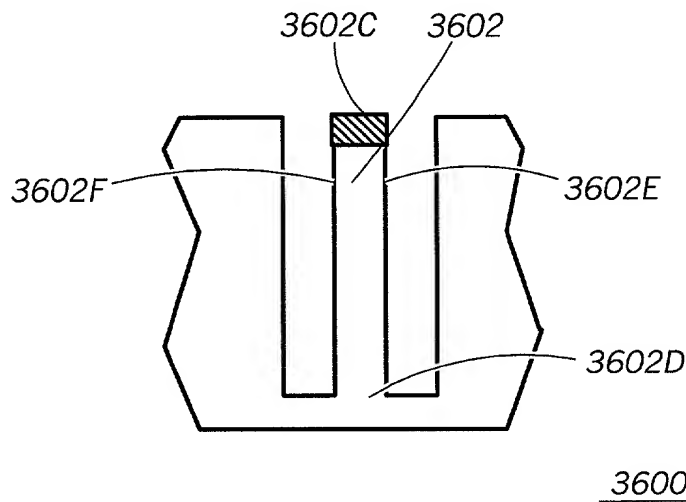


FIG. 37

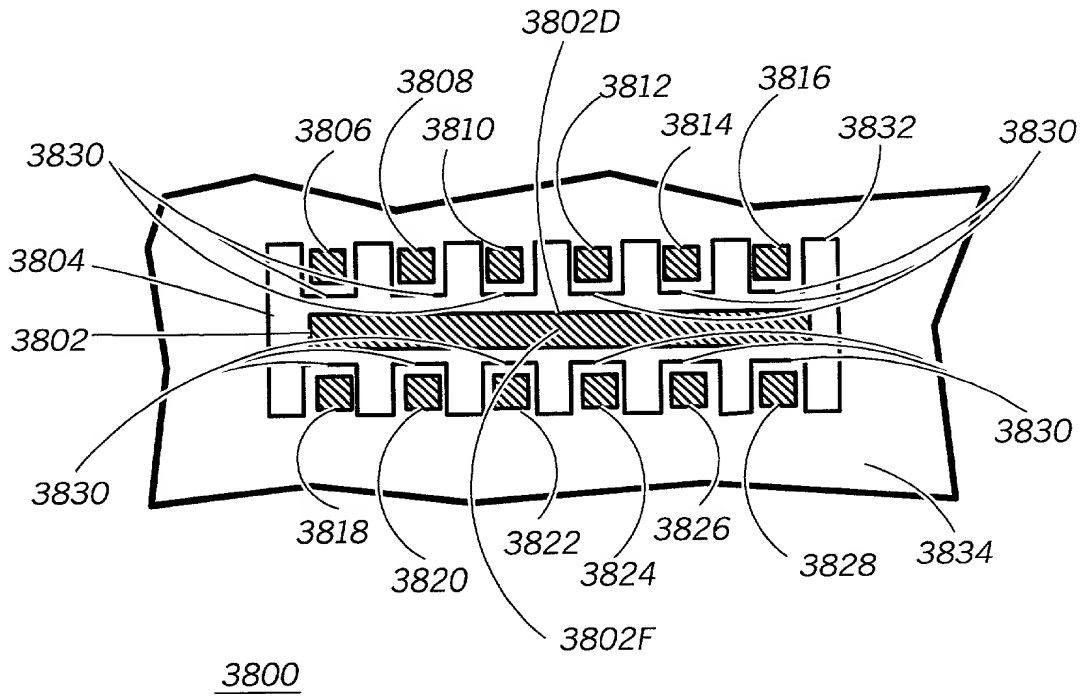


FIG. 38

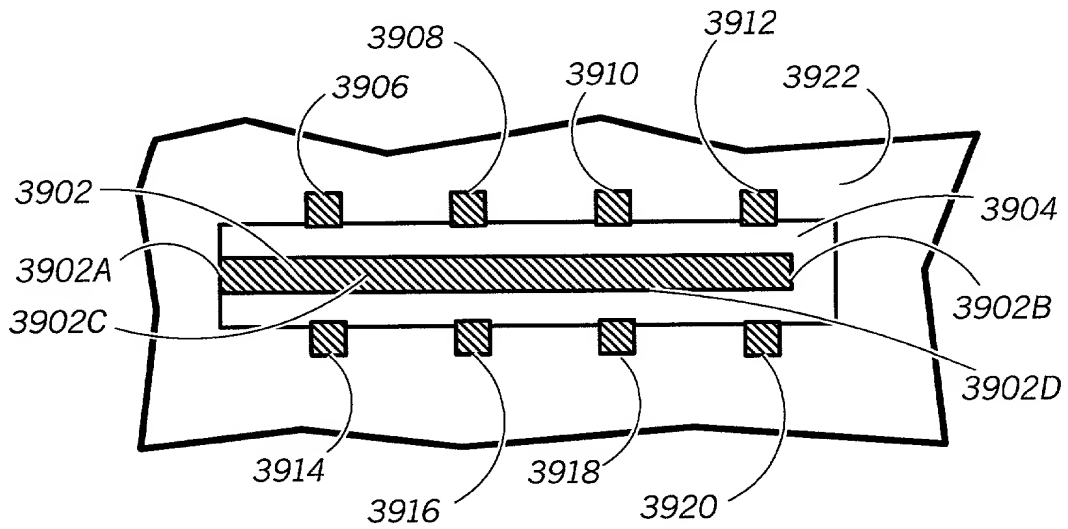


FIG. 39

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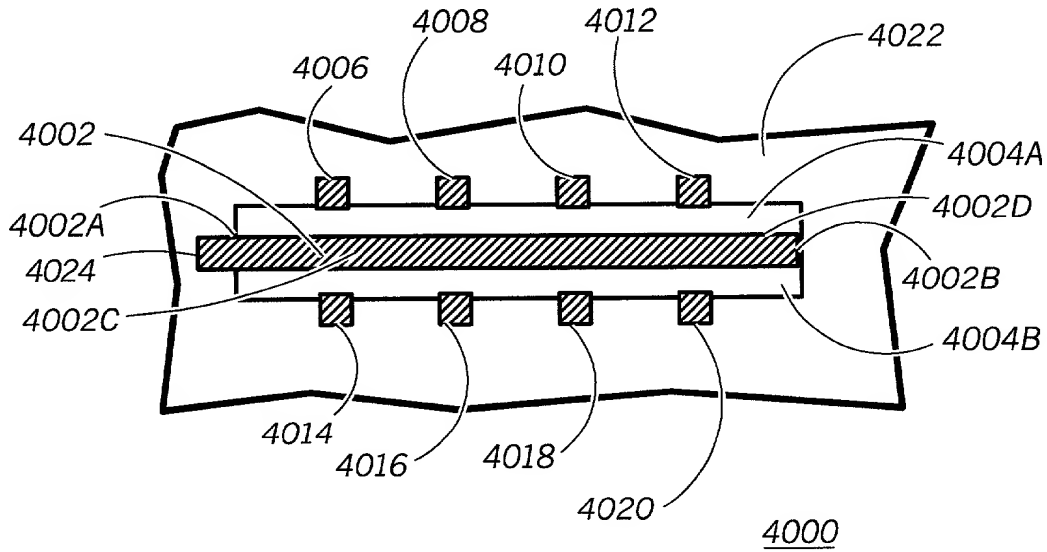


FIG. 40

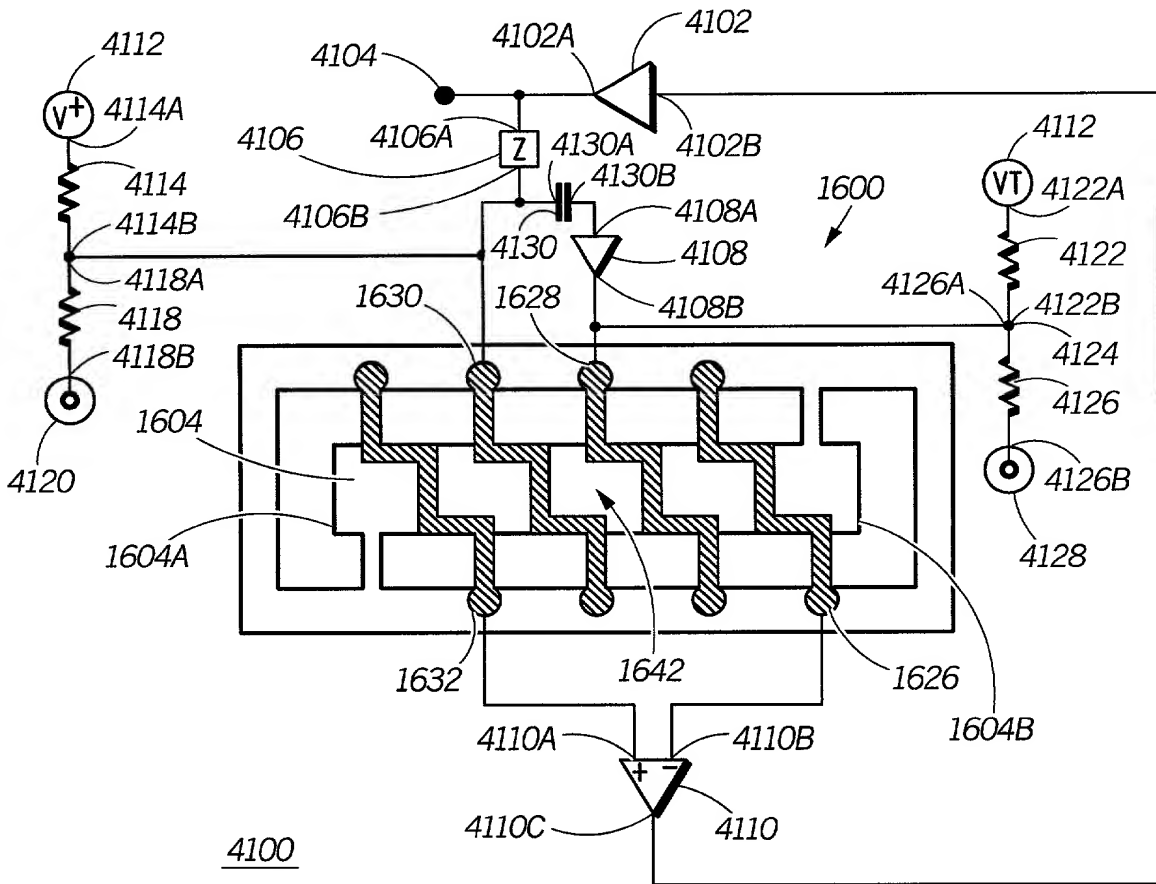


FIG. 41

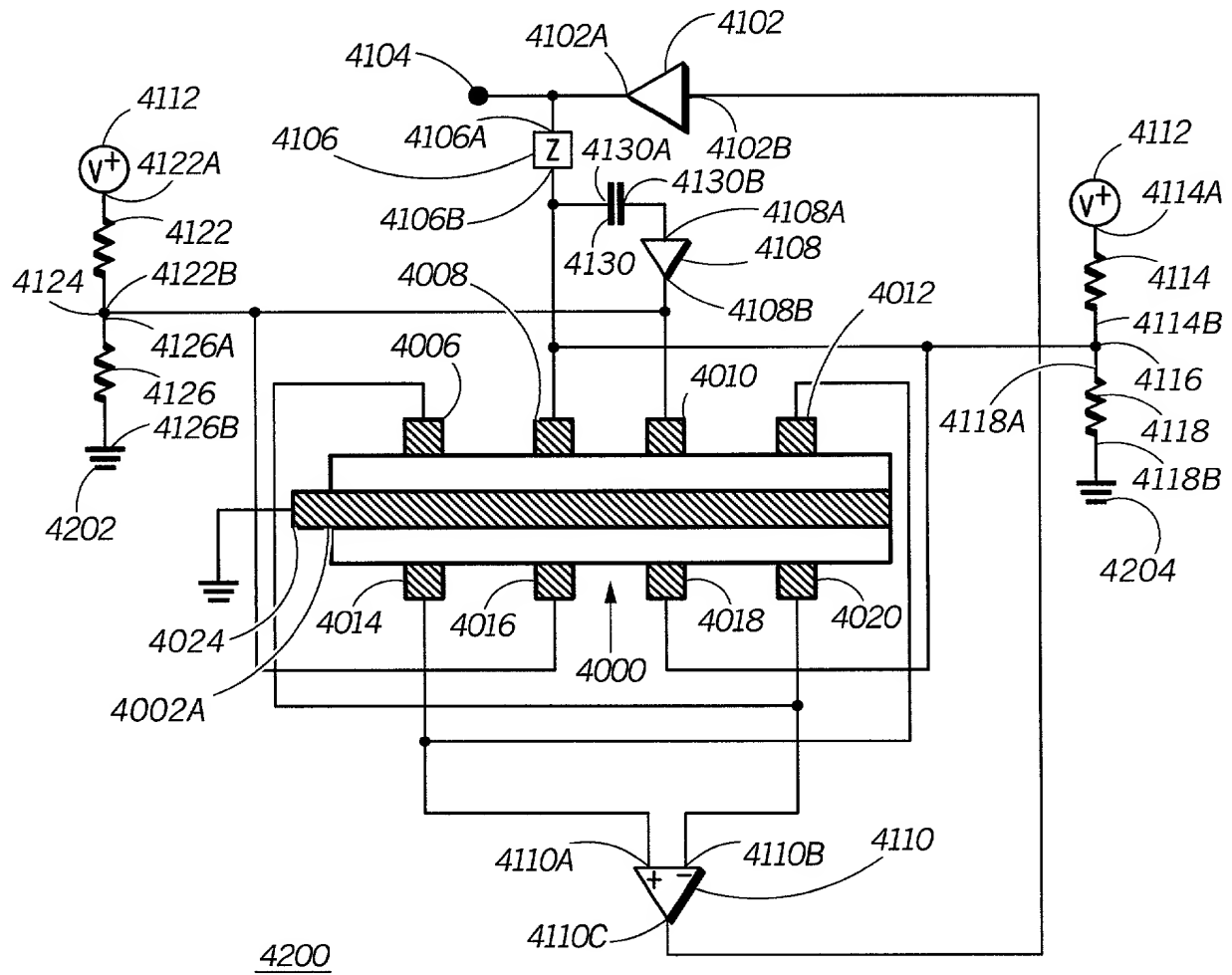


FIG. 42